

Applications by means of the accelerator technologies based on cERL



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(KEK)



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- Summary

Original proposal of the applications on the cERL

- Laser Compton Scattering x- or γ -ray (LCS) production for the future application in collaboration with JAEA
- THz production by means of bunch compression techniques

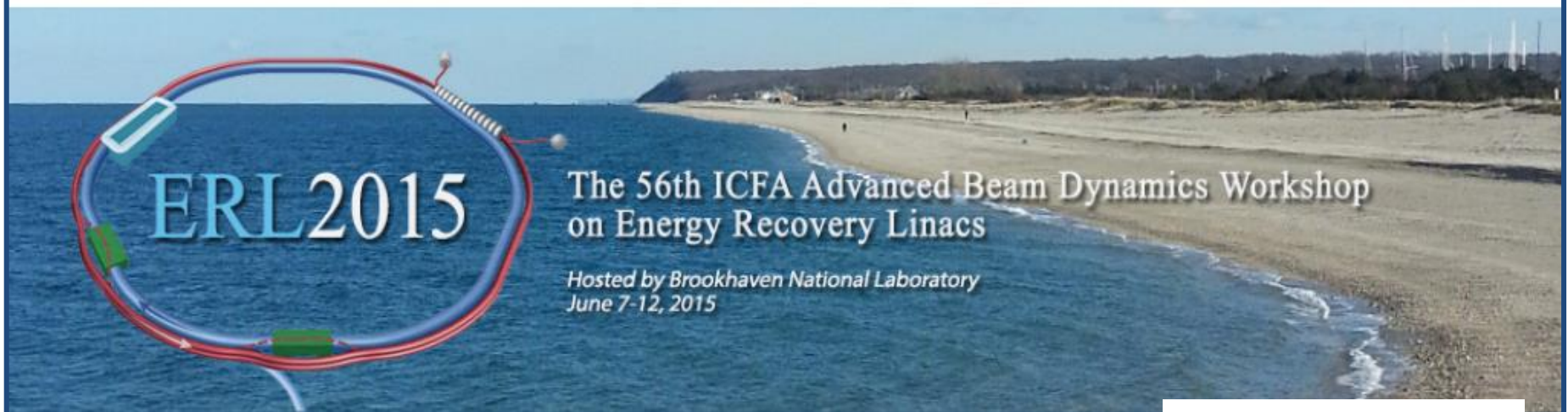
Laser Compton Sources Based On Energy Recovery Linacs

Ryoichi Hajima

Japan Atomic Energy Agency

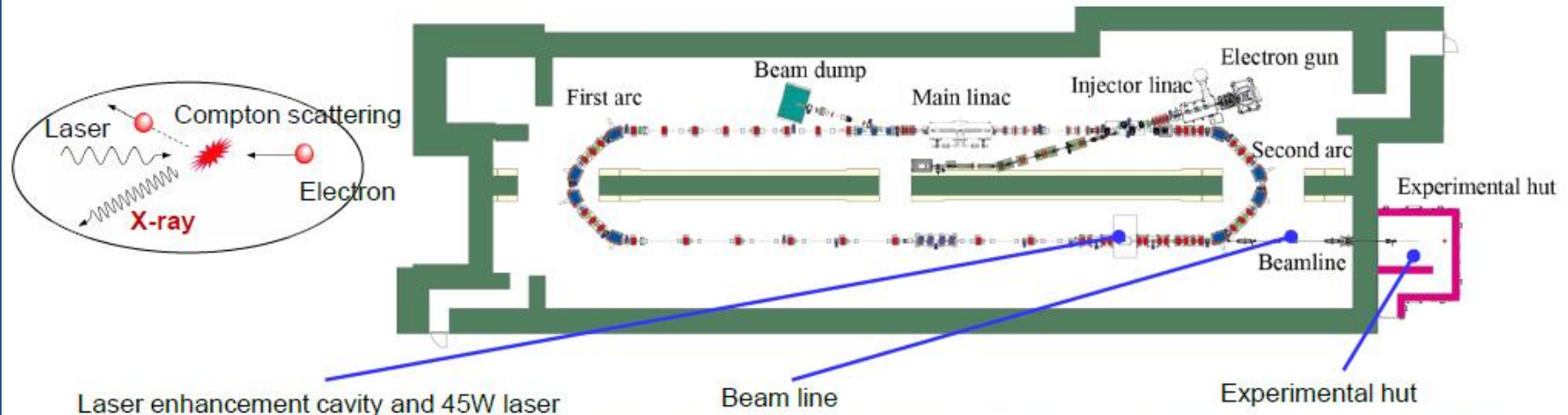
June 10, 2015

ERL-2015 WS

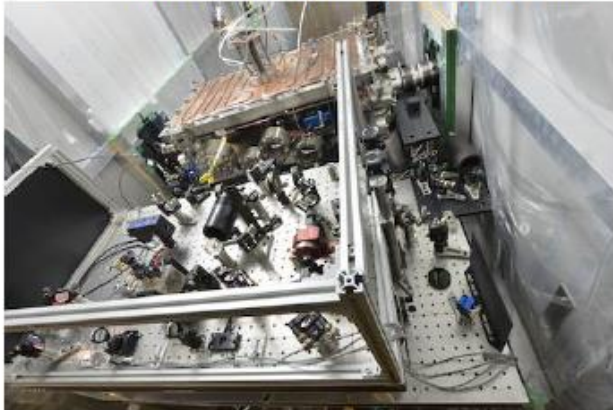


LCS Experiment at Compact ERL

Demonstration of technologies relevant to future ERL-based LCS sources



Laser enhancement cavity and 45W laser



Beam line



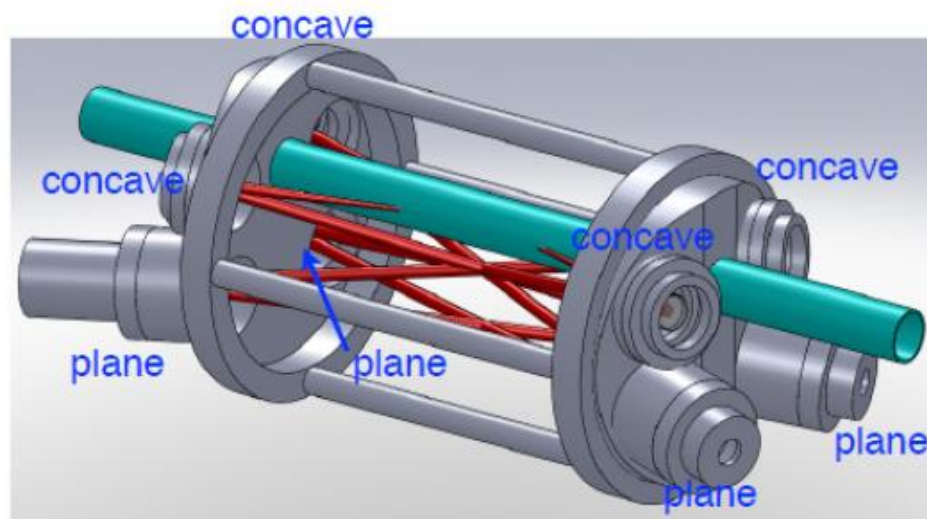
Experimental hut



Work supported by:

A government (MEXT) subsidy for strengthening nuclear security (R. Hajima, JAEA), and Photon and Quantum Basic Research Coordinated Development Program from the MEXT (N. Terunuma, KEK)

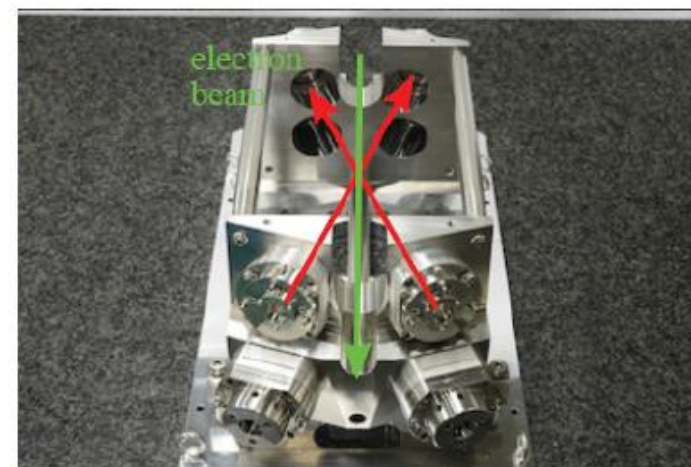
Laser Enhancement Cavity



Developed by T. Akagi (KEK)

T. Akagi et al., Proc. IPAC-2014, p.2072

A. Kosuge et al., Proc. IPAC-2015, TUPWA-66

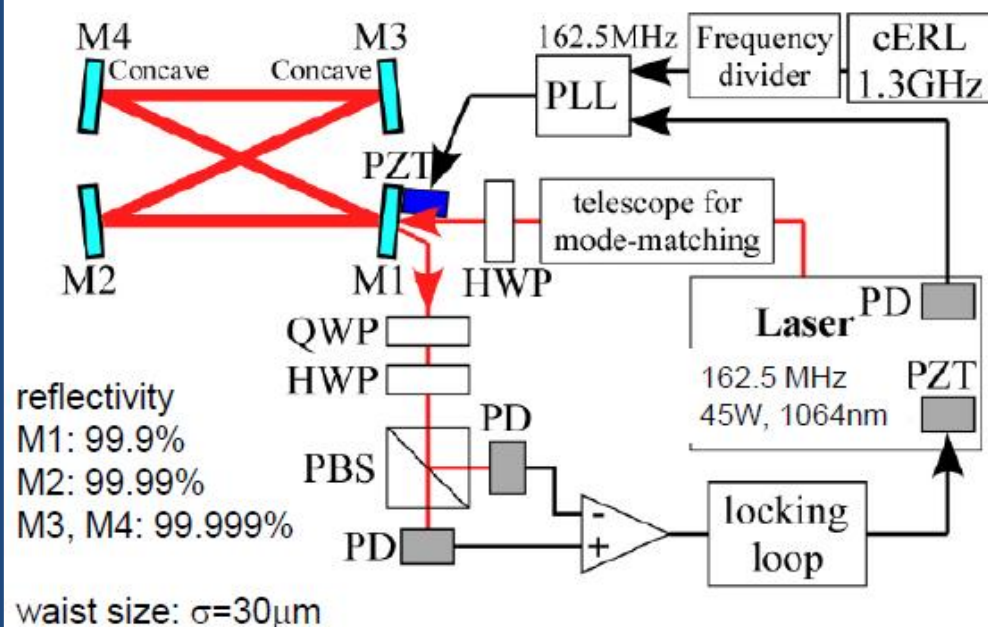


Can store two beams independently



Fast polarization switch at 325 MHz
or
Double the laser power at LCS

(Single laser for the first experiment)



Beam Optics for the LCS

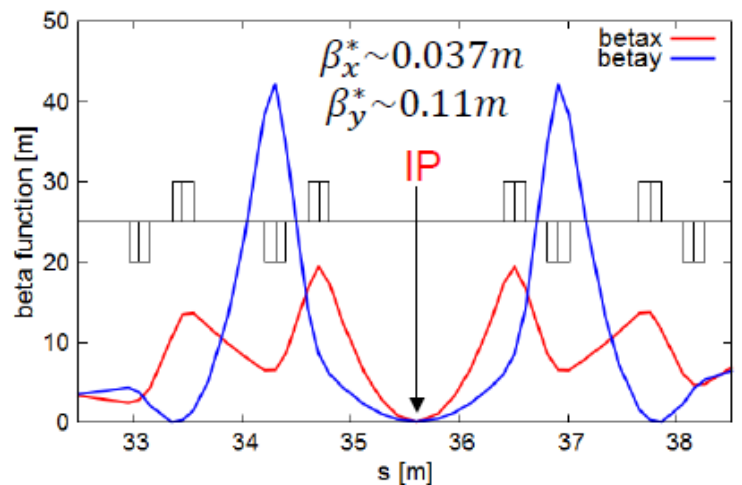
- Low-beta insertion for small beam sizes at IP
- Transport beams to the dump with small beam losses

Beam optics was established

IP: interaction point

Design optics (example: "70% middle" optics)

$\sigma_x^* = 21 \mu\text{m}$, $\sigma_y^* = 33 \mu\text{m}$ at IP

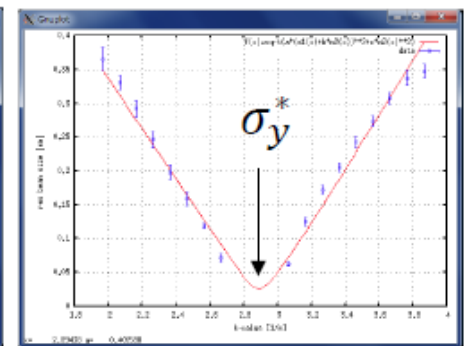
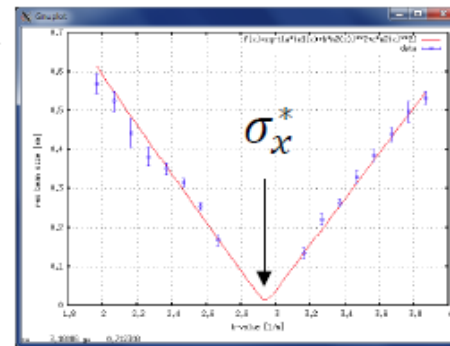


Beam size at the screen monitor



Beam sizes at IP were estimated from Q-scan data

$\sigma_x^* \sim 13 \mu\text{m}$, $\sigma_y^* \sim 25 \mu\text{m}$ (example)



K-value of QMLC04

K-value of QMLC04

σ_x^* , $\sigma_y^* < (\text{resolution of the screen monitor})$

Bunch charge: 0.5 pC/bunch,
Normalized emittances: $(\epsilon_{nx}, \epsilon_{ny}) = (0.47, 0.39)$ mm-mrad

S. Sakanaka et al., Proc. IPAC-2015, TUBC1 14

X-ray Produced by LCS

Parameters of electron beams:

Energy [MeV]	20
Bunch charge [pC]	0.36
Bunch length [ps, rms]	2
Spot size [μm , rms]	30
Emittance [mm mrad, rms]	0.4
Repetition Rate [MHz]	162.5
Beam current [μA]	58

Parameters of laser (enhanced by cavity):

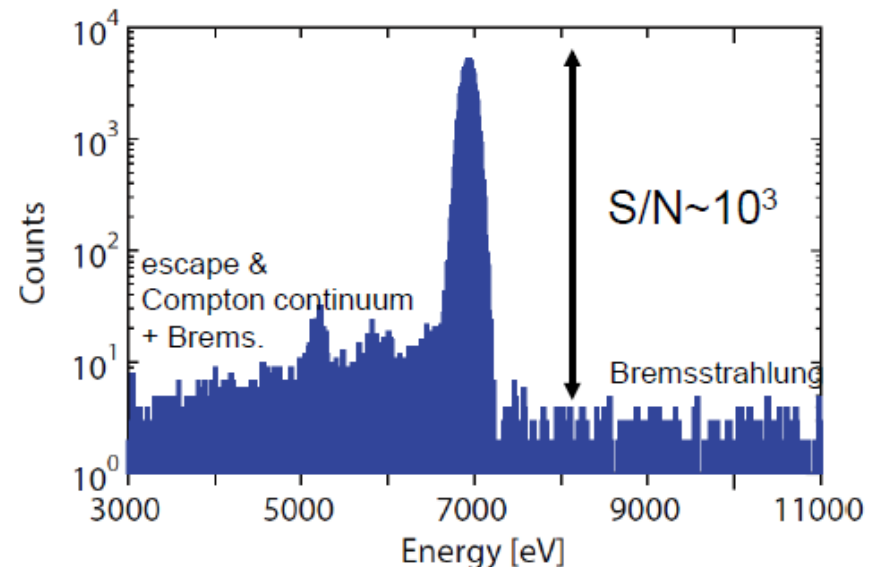
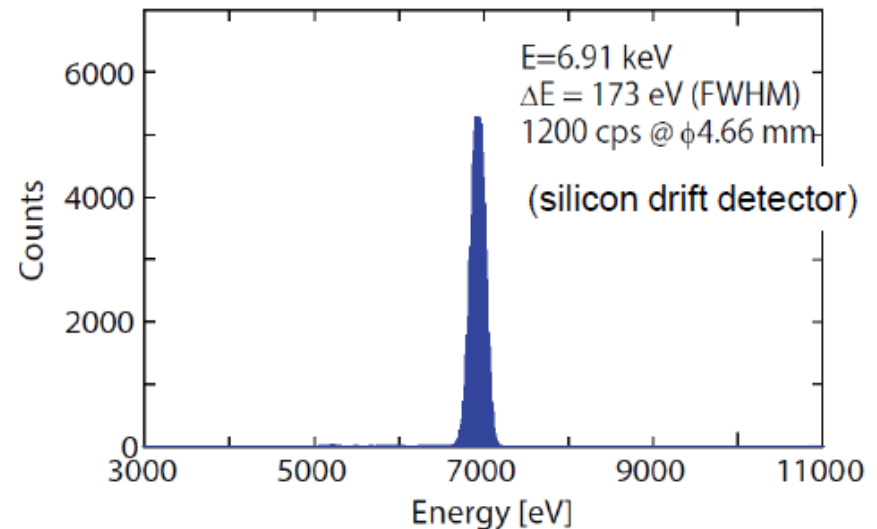
Center wavelength [nm]	1064
Pulse energy [μJ]	64
Pulse length [ps, rms]	5.65
Spot size [μm , rms]	30
Collision angle [deg]	18
Repetition rate [MHz]	162.5
Intracavity power [kW]	10

Results:

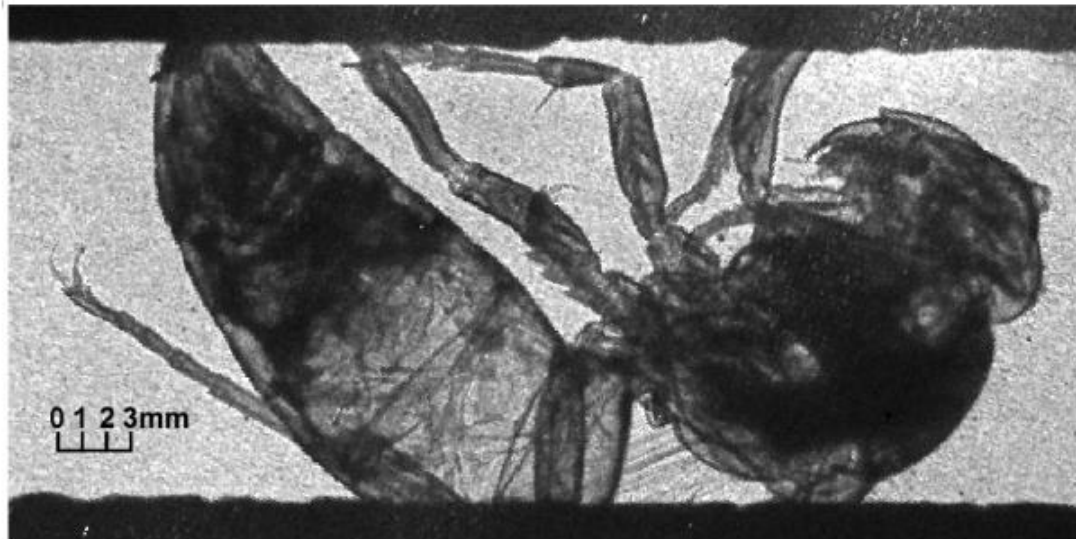
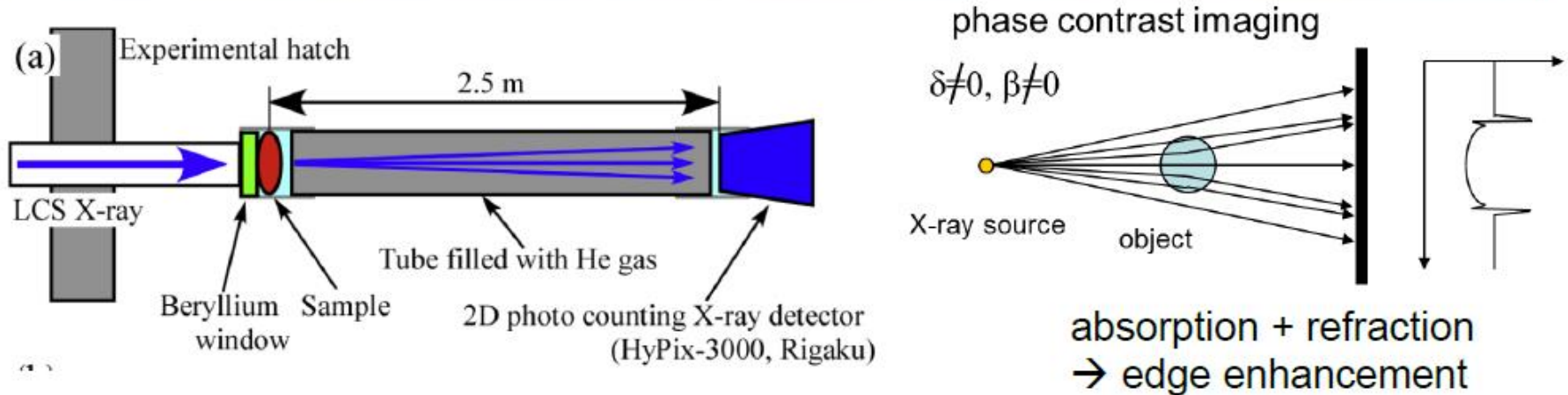
Photon energy = 6.9 keV
Detector count rate = 1200 cps @ ϕ 4.66mm (*)
Source flux = 4.3×10^7 ph/s (**)

(*) Detector collecting angle is $4.66\text{mm}/16.6\text{m} = 0.281$ mrad

(**) CAIN/EGS simulations with the detector count rate



X-ray imaging with a LCS beam



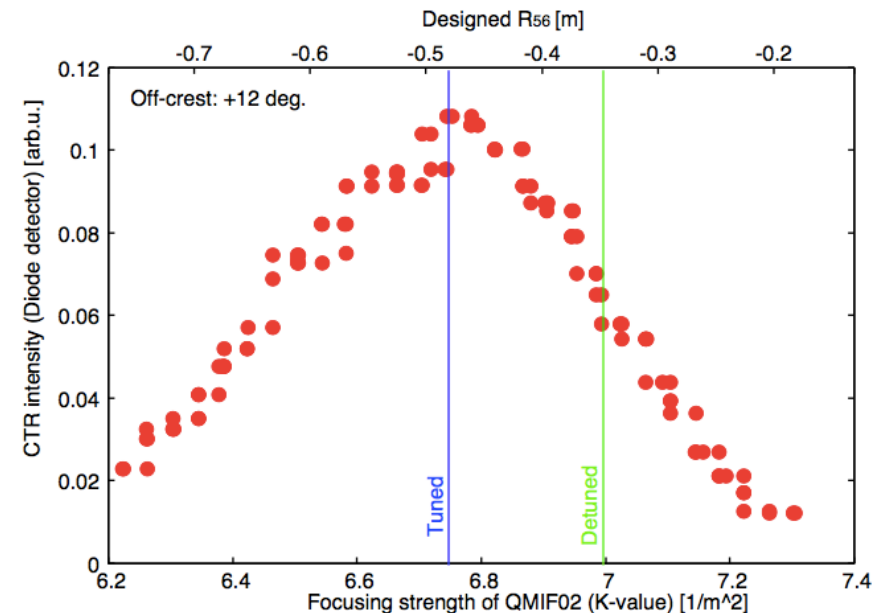
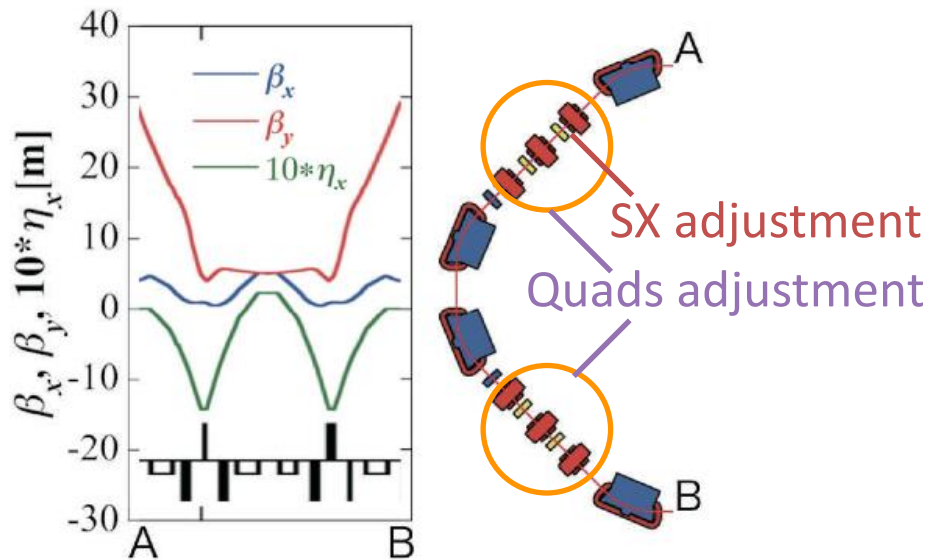
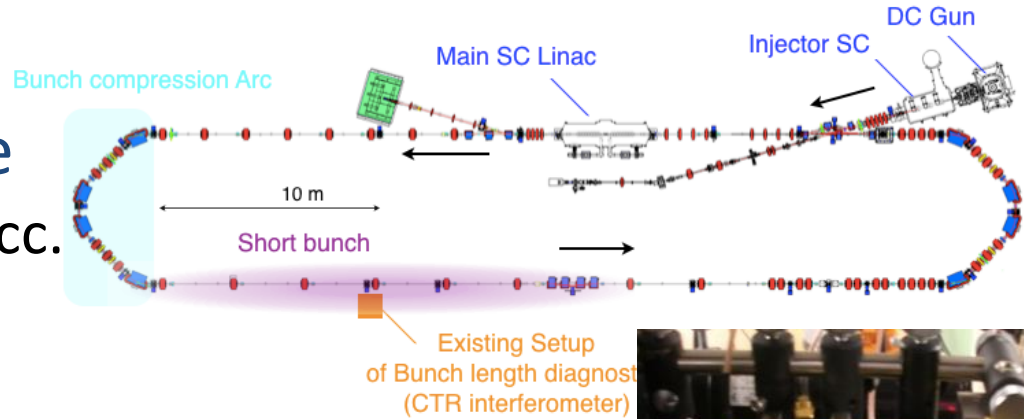
An X-ray image of a hornet taken with LCS-produced X-ray.
Detector: HyPix-3000 from RIGAKU. Detector was apart from the sample by approx. 2.5 m.

Production of THz radiation

Bunch compression tuning

Courtesy of Y. Honda

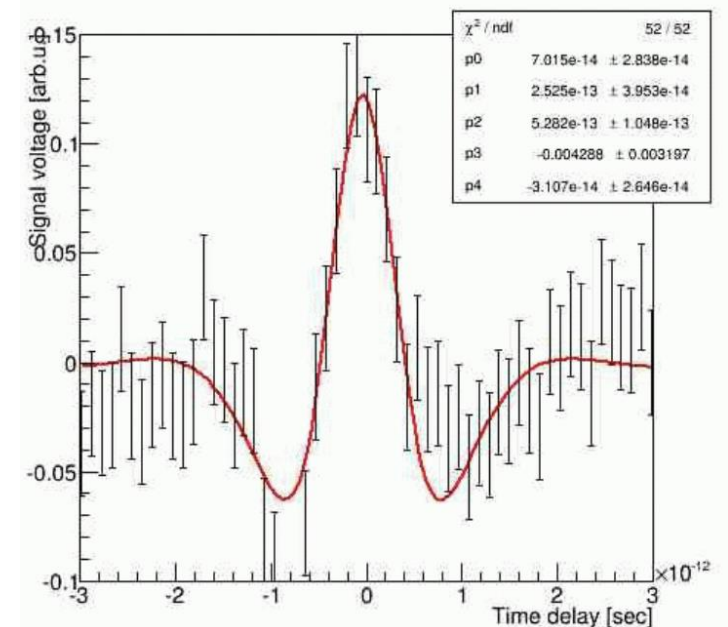
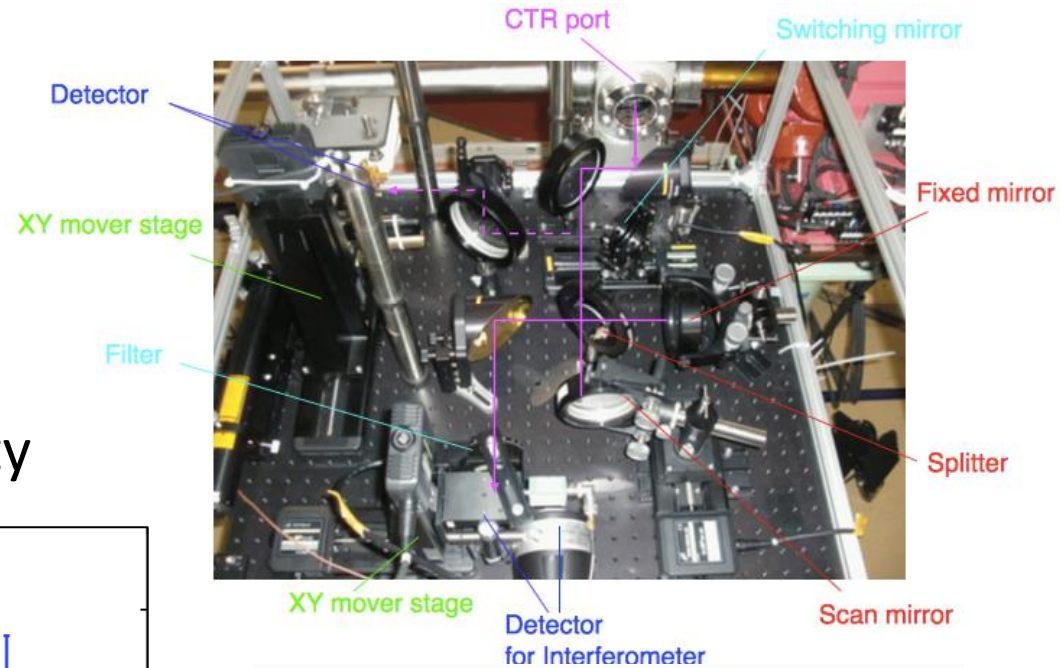
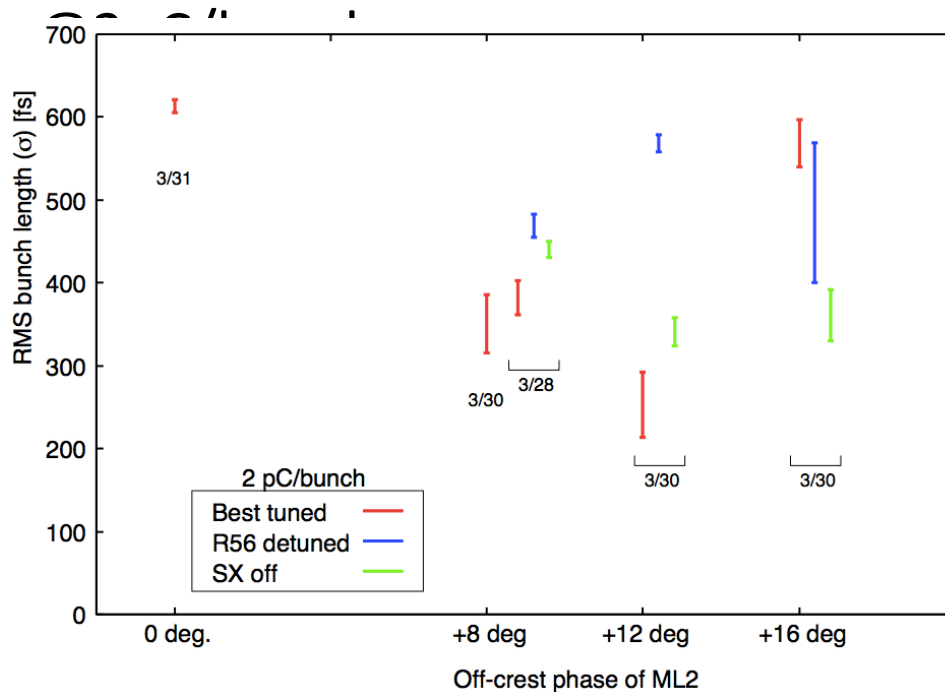
- Beam tuning procedure
 - Set Main linac Off-crest acc.
 - Scan the arc optics
 - R56 by Q combination
 - SX
 - Referring CTR intensity



Bunch length and THz measurement

Courtesy of Y. Honda

- Michelson interferometer at CTR port.
- Spectrum reaching $\sim 1\text{THz}$
- Bunch length 250fs (RMS) is realized in good reproducibility



Change the target from academia to industry

2016 The future light source was shifted to the high-performance ring accelerator, so that there is no back ground to continue the ERL R&D. On the other hand, KEK directorates kept the importance of the R&D for industrial application based on ERL technologies*). High bunch charge test operation was approved at the end of the fiscal year 2016.

2017 ERL project Office was closed in KEK and “Utilization Promotion Team based on Superconductive Accelerator” was kept in Department of future Accelerator and detector technologies in KEK.

*Reference) KEK Project Implementation Plan (KEK-PIP)

<http://www.kek.jp/ja/NewsRoom/Release/20160802141100/>

3-2. Other research projects carried out using general funds of KEK

The following projects have up to now been conducted mainly using general funds of KEK. They will be continued on the condition that greater efforts are made to obtain external funding.

- Simulation studies with the existing supercomputer (only up to summer of 2017)
- Industrial application of ERL technology
-

Industrial Application of ERL technology

ERL gives us a following outstanding performance on Accelerator.

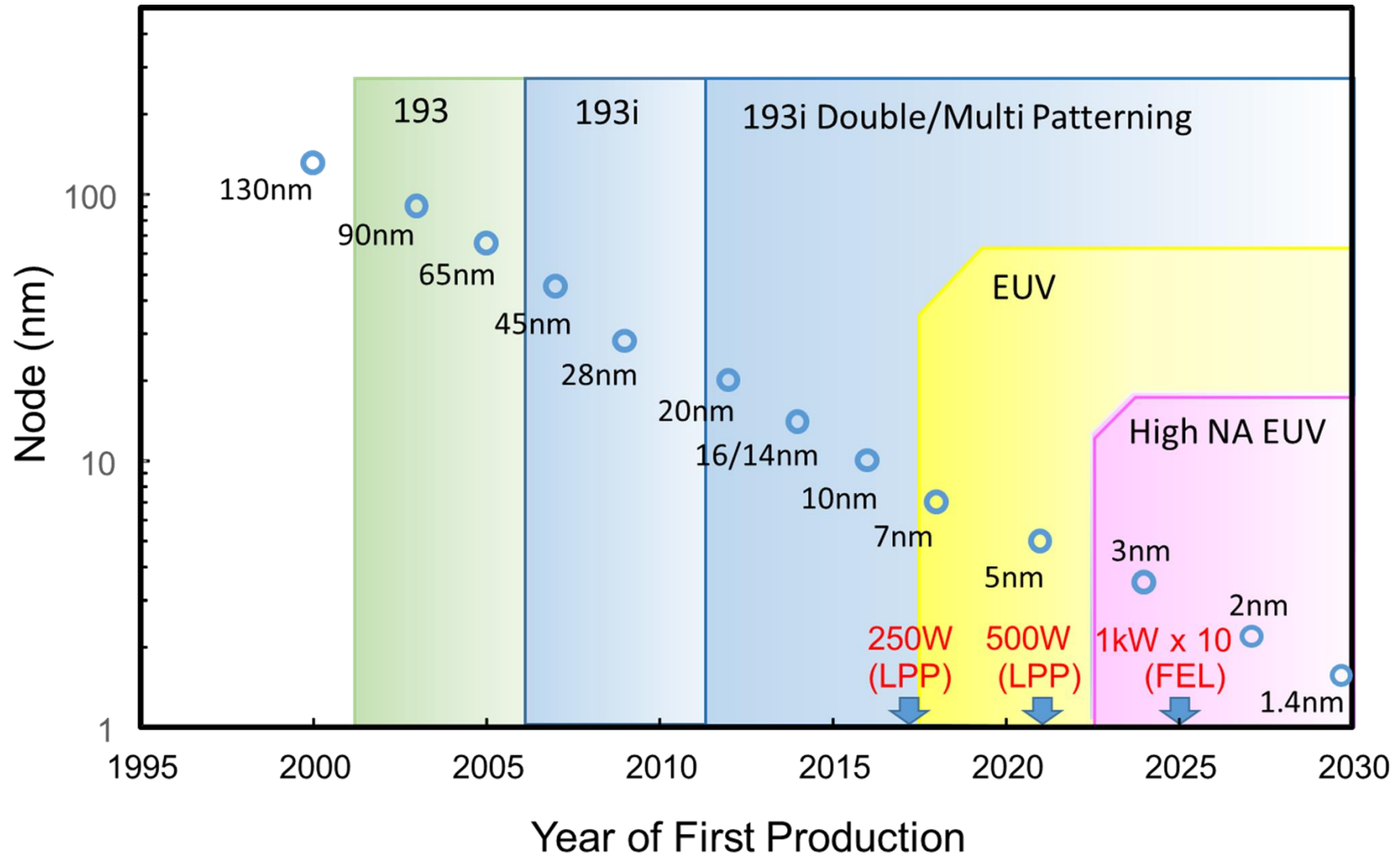
- High current linac-based electron beam
 - Production of the high intense quantum beam
- High quality of the electron beam :
 - Small Emittance, Short pulses, and so on
 - The quantum beams have excellent performance on energy and space resolution.



EUV-FEL for Lithography, High intense LCS sources
and so on

1. EUV-FEL for Lithography

(Back ground)



Technology node trend of Logic LSI and expected power on EUV light source

Present Status and Future Development on EUV Lithography

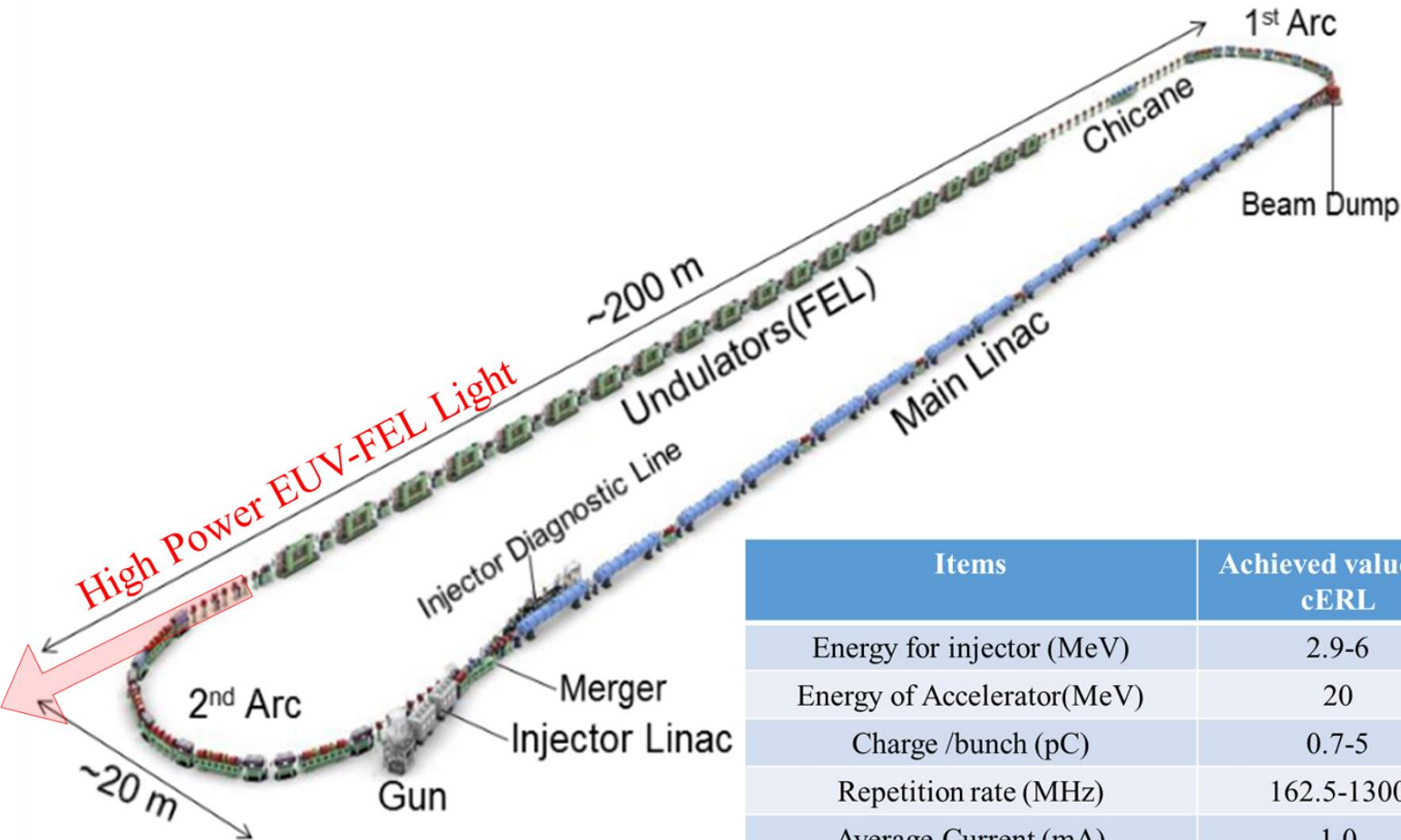
Present Status

- The technologies on EUV Lithography system based on LPP light source are progressing, now.
- The system based on ~ 200 W LPP light source is starting point of the production phase.

Future Development

- It is expected that these on ~ 1 kW source will be necessary to realize the production less than 3 nm node, too.
- It is important to develop new type light source to realize higher power than ~ 1 kW, and also the other technologies.

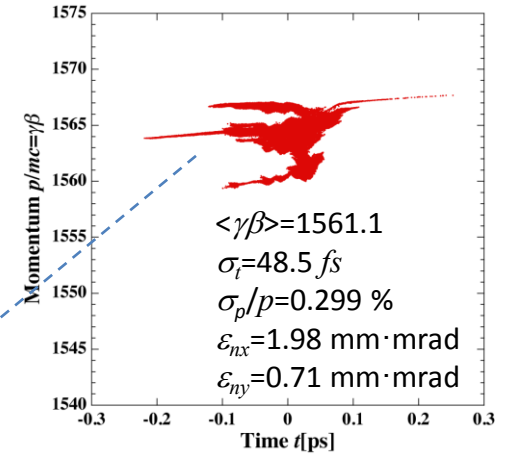
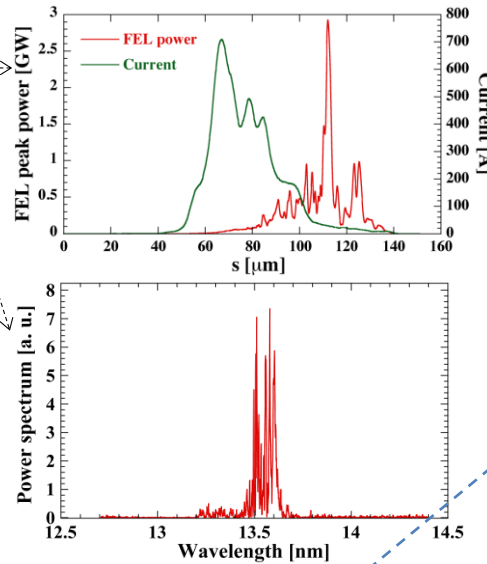
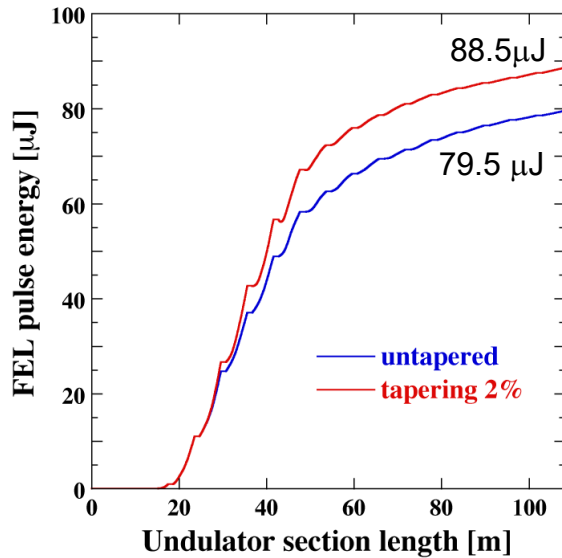
Prototype design of the EUV-FEL



Items	Achieved values in cERL	Design Values at the EUV-FEL
Energy for injector (MeV)	2.9-6	10.5
Energy of Accelerator (MeV)	20	800
Charge /bunch (pC)	0.7-5	60
Repetition rate (MHz)	162.5-1300	162.5
Average Current (mA)	1.0	9.75
Emitance for electron beam (mm mrad)	0.3-1	0.6
Gradient of the accelerated energy (MV/m)	8.6	12.5
Wavelength of EUV-FEL (nm)	/	13.5
Average power of EUV-FEL (kW)	/	Higher than 10 kW

FEL Performance

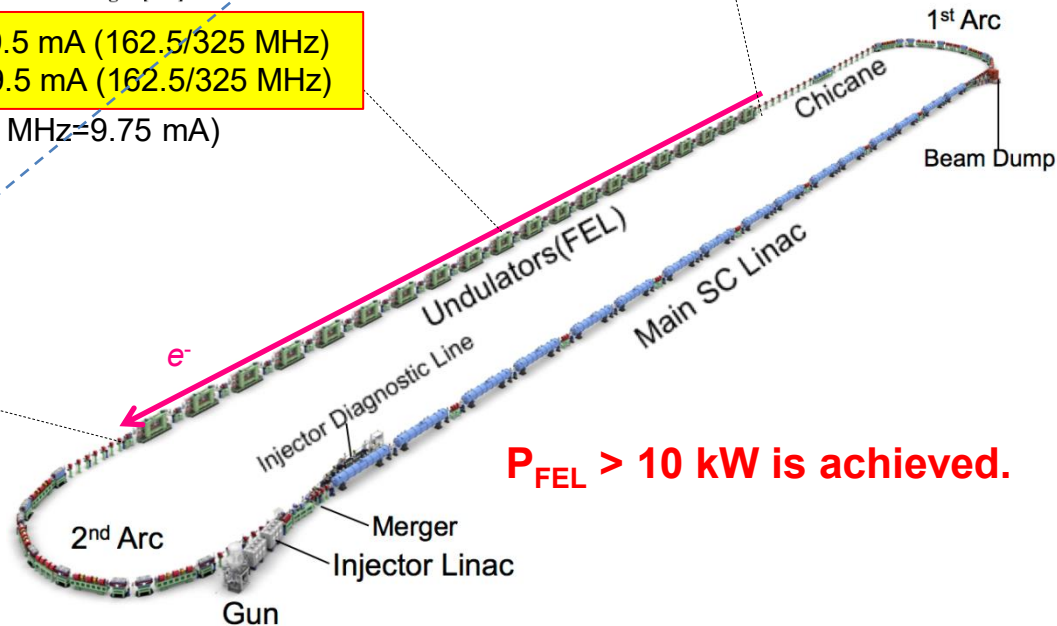
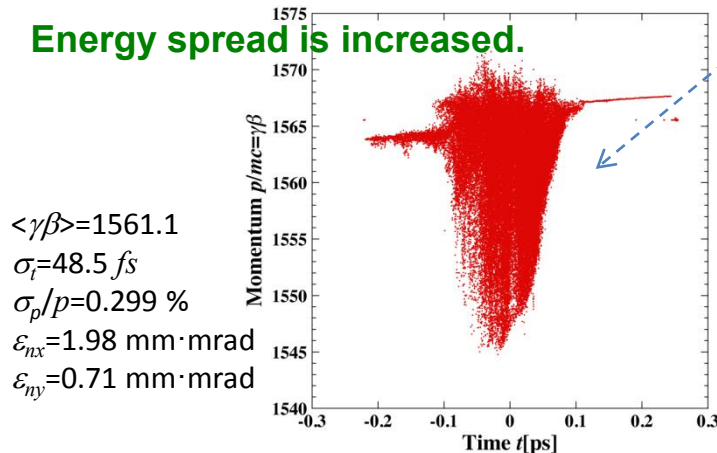
BY N. Nakamura: This workshop



FEL power without tapering: 12.9/25.8 kW @ 9.75/19.5 mA (162.5/325 MHz)
 FEL power with 2% tapering: 14.4/28.8 kW @ 9.75/19.5 mA (162.5/325 MHz)

($P_{\text{FEL}}=84\text{ }\mu\text{J} \times 162.5\text{ MHz}=13.7\text{ kW}$, $I_{\text{av}}=60\text{ pC} \times 162.5\text{ MHz}=9.75\text{ mA}$)

Energy spread is increased.



$P_{\text{FEL}} > 10\text{ kW}$ is achieved.

2. High resolution X-ray imaging device for medical use

From the view point of neurosurgery Courtesy of K. Hyodo

Intravascular surgery of neurosurgery

coil: Stuffed aneurysm and stop bleeding

Stent: Support stabilizing coil

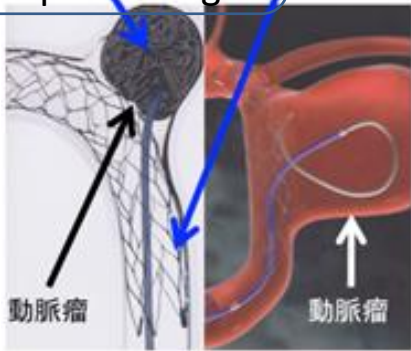
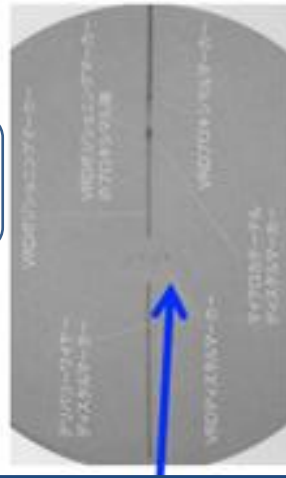


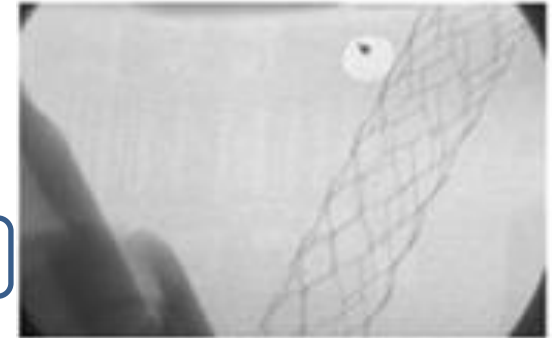
Image under surgery

The stent can not be seen



Using a large synchrotron radiation facility

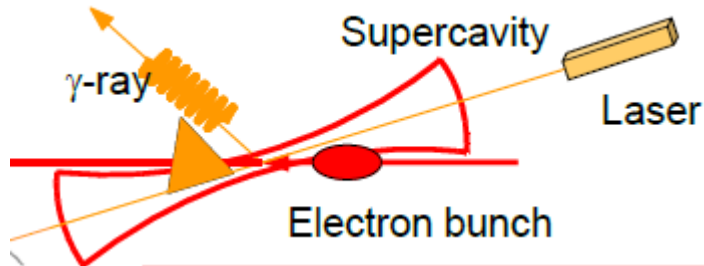
High resolution



Stents can be clearly visualized

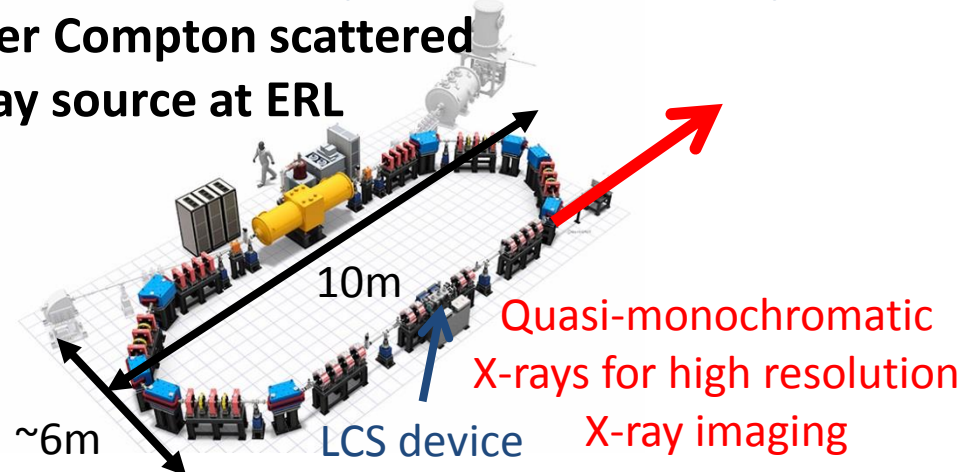
Provided by the Department of Neurosurgery, University of Tsukuba

If we can make a compact high-resolution X-ray source in a hospital!



Potential of quasi-monochromatic X-rays for high resolution X-ray imaging by laser Compton scattering (LCS)

Laser Compton scattered X-ray source at ERL



2. High resolution X-ray imaging device for medical use

Feasibility from the experimental result on cERL

Courtesy of K. Hyodo

- Success of LCS at cERL (March/2014) (high resolution X-ray imaging) (20MeV, 0.1 mA, 10kW laser Cavity)

<http://www.kek.jp/ja/NewsRoom/Release/20150427150000/>

Result of March/2014

X-ray Energy 7keV
Exposure time 600sec

Main issues for medical application

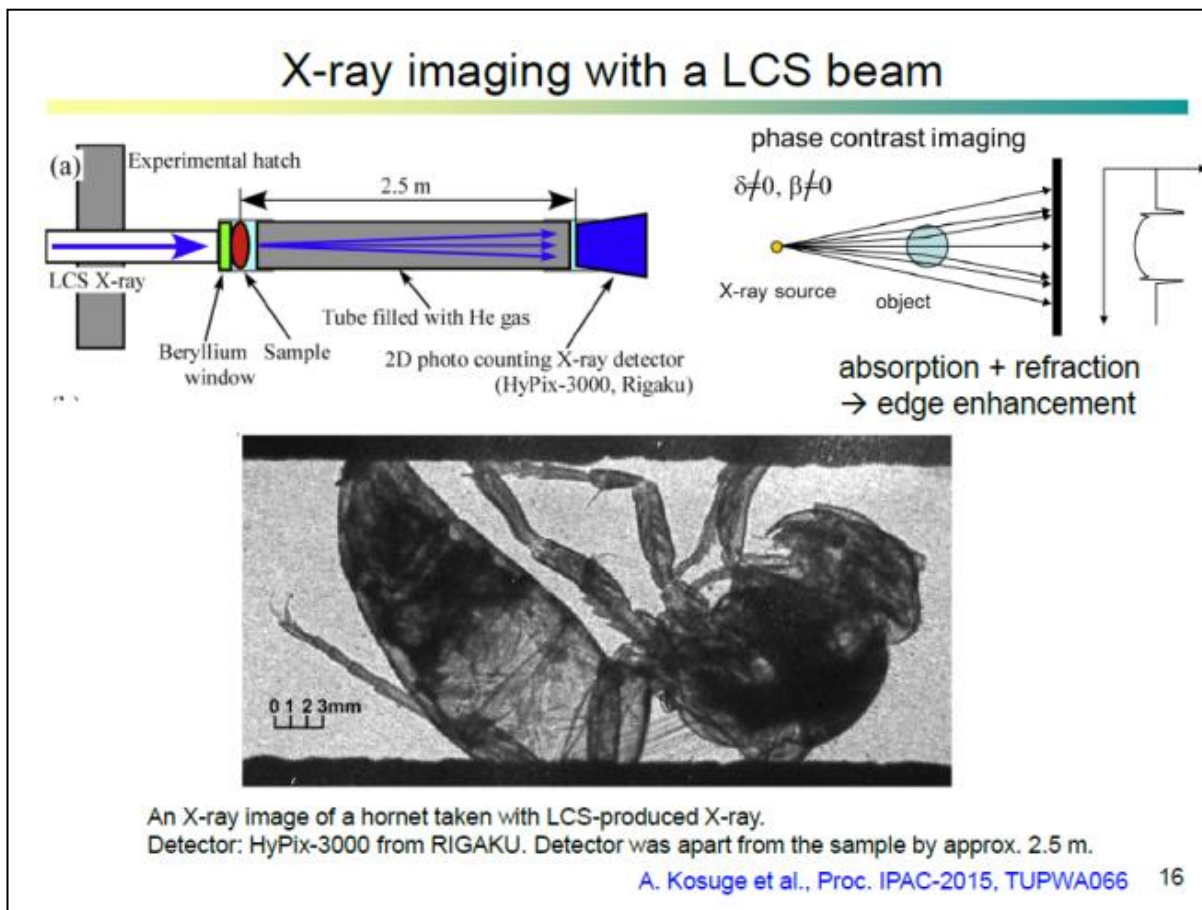
- 1) Too long exposure time
- 2) Too low Energy

(50MeV, 10 mA,
>100kW laser Cavity)



X-ray Energy ~40 keV
Exposure time <0.1 sec

Starting point of medical application



3. Nuclear security system

Courtesy of R. Hajima

(Non-destructive Detection and Measurement of Nuclear Material by Laser Compton Scattering Gamma Ray)

Necessity of non-destructive detection and measurement of nuclear material

1) Deterrence of terrorism using nuclear material

- Confront terrorism with an international framework (nuclear security summit)
- Border strategy to investigate the nuclear material is essential against nuclear terrorism.



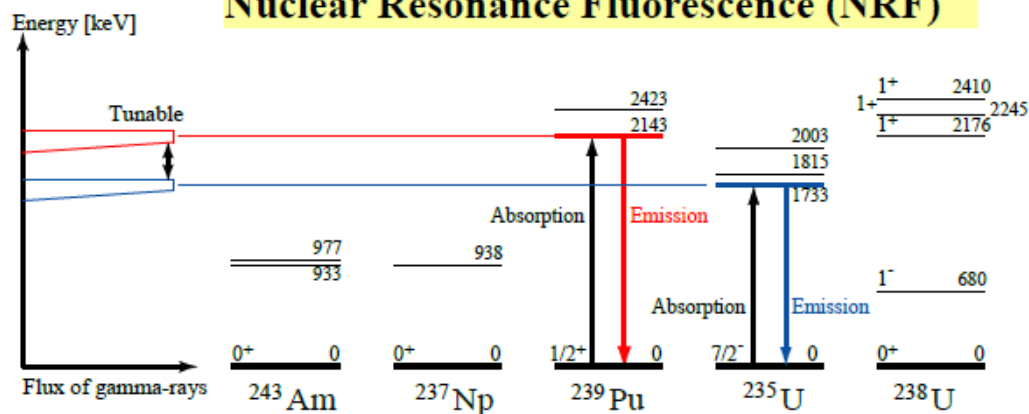
2) Nuclear nonproliferation

- Melted fuel will be taken from Fukushima Nuclear Power plant from 2021
- Nuclear material measurement of melted fuel is essential

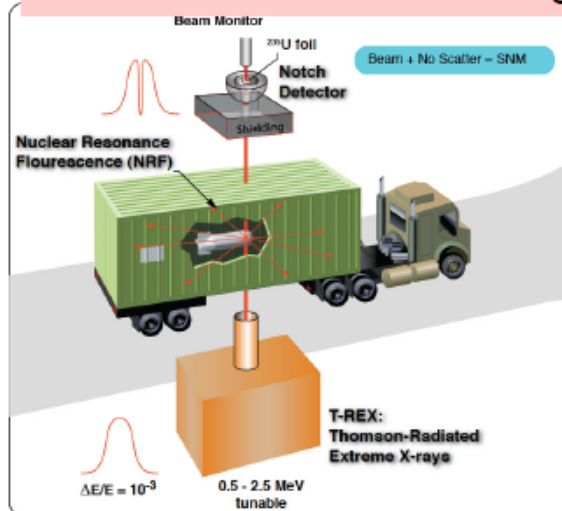


Nondestructive Detection & Measurement of Nuclear Material

Nuclear Resonance Fluorescence (NRF)

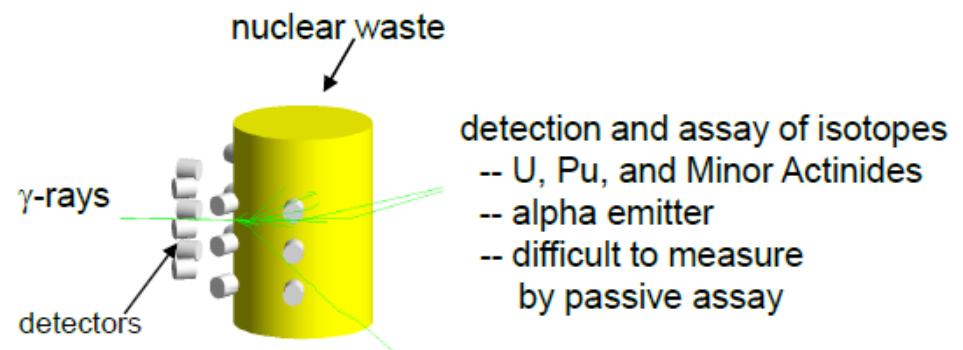


Detection of SNM in a cargo



SNM: special nuclear material

Management of nuclear material



R. Hajima et al., J. Nucl. Sci. Tech. 45, 441 (2008)
J. Pruet et al., J. App. Phys. 99, 123102 (2006)

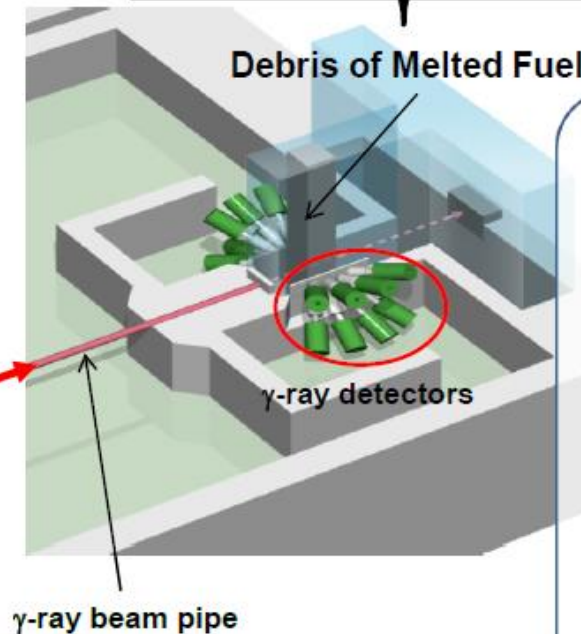
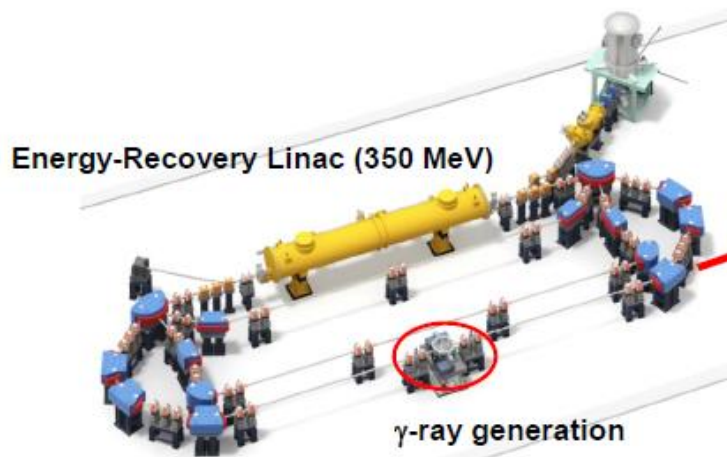
LCS γ -ray for Fukushima

Measurement of Pu in the melted fuel

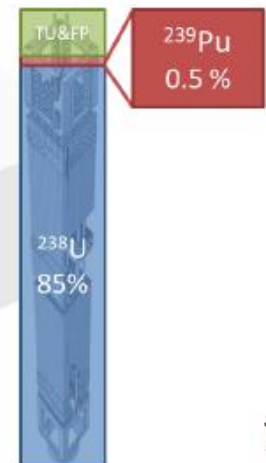
→ necessary for nuclear nonproliferation!



removal of debris
from the core ~2022



^{239}Pu Small Fraction
of Spent Fuel



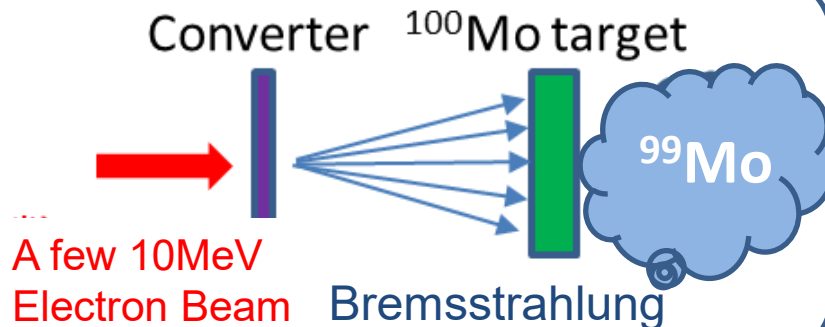
4. RI manufacturing facility for nuclear medical examination ($^{99}\text{Mo}/^{99\text{m}}\text{Tc}$)

Courtesy of K. Umemori

Concern about the stable supply of ^{99}Mo / $^{99\text{m}}\text{Tc}$

- ^{99}Mo is almost 100% imported, even though the largest number of applications in nuclear medicine diagnosis
- Problem of the stable air transportation
(Problem caused by volcanic eruption in the past)
- Most ^{99}Mo is manufactured in nuclear reactor
- Due to the aging of nuclear reactors, stable supply in the future is a big issue

Development of RI manufacturing (^{99}Mo / $^{99\text{m}}\text{Tc}$) by using accelerator for stable supply



Required Specification
for accelerator

- 20 ~ 50 MeV electron beam
- Several mA to 10 mA

Summary

- ERL gives us high current linac-based electron beam ($\sim 10\text{mA}$) with high quality of the electron beam such as small emittance, Short pulses.
- The unique performance gives us several important industrial applications.